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## Optical Materials





Research Article

# Tunability of nonlinear optical properties of amorphous Cu–Al–O films induced by thermal oxidation

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## ABSTRACT

A series of Cu–Al–O thin films with excellent nonlinear absorption properties were prepared by magnetron sputtering at room temperature. An absorption peak at around 440 nm was observed in the as-deposited thin films, with CuAlO<sub>2</sub> as the main phase. After thermal oxidation at 400 °C, the surface roughness of the films decreased, the absorption peak was blue-shifted, with the optical band gap increased. Open aperture Z-scan measurements revealed that the as-deposited samples had strong saturable absorption and reached the maximum nonlinear absorption coefficient ( $\beta$ ) of  $-6.29 \times 10^{-5}$  cm/W. The nonlinear optical conversion from saturable absorption to reverse saturable absorption was observed in as-annealed samples with *β* values up to 2.592 × 10<sup>-5</sup> cm/W. In addition, the time-domain finite-difference simulation results were basically consistent with those of the experimental results.

#### **1. Introduction**

Transparent conductive oxides (TCOs) have become one of the research hotspots in the field of optoelectronics in recent years due to their high conductivity and transmittance in the visible light region [[1](#page-5-0), [2](#page-5-0)], widely used in solar cells, flat panel displays, light-emitting diodes, electromagnetic shielding and touch panels [\[3,4](#page-5-0)]. For a long time, the production and application of TCOs mainly focus on ITO, AZO, FTO and so on. The research and development of novel TCOs by researchers from all over the world have never stopped.

In 1997, Kawazoe et al. [\[1\]](#page-5-0) first reported in Nature, which aroused global attention to the new transparent conductive oxide  $CuAlO<sub>2</sub>$  and set off a research boom. Since then, some novel TCOs such as LaCuOS, CuGaO2, CuCrO2 were proposed by substitution doping. In order to optimize the preparation process to improve the conductivity of  $CuAlO<sub>2</sub>$ , so far, the reported preparation methods mainly include pulsed laser deposition [[5](#page-5-0)], sputtering deposition [\[6](#page-5-0)], sol-gel [\[7\]](#page-5-0), solid-phase synthesis [\[8\]](#page-5-0), vapor deposition [\[9\]](#page-5-0), etc. Compared with other preparation techniques, magnetron sputtering has the advantages of fast deposition speed, good density, good uniformity and so on, which can be applied to large-scale deposition. In 2014, Ping-Hung Hsieh et al. [[10](#page-5-0)] reported the effect of different sputtering power on the growth of CuAlO<sub>2</sub>. Furthermore, high temperature annealing is the decisive step in the formation of CuAlO<sub>2</sub> thin films  $[11-13]$  $[11-13]$ , which is the most commonly used post-treatment method. In recent years, most of the reports on CuAlO<sub>2</sub> thin films are doping, fine preparation and post-processing to improve thermoelectric properties, optimize optical properties, accelerate crystallization and improve purity  $[14,15]$  $[14,15]$  $[14,15]$ . However, the research on the nonlinear optical properties of CuAlO<sub>2</sub> has not been reported yet.

Nonlinear optics (NLO) plays an important role in the study of the interaction between light and materials. Z-scan technology has been widely used because of its simple device and high sensitivity, and it can separate the nonlinear absorption coefficient (*β*) and the nonlinear refractive index [[16\]](#page-6-0). Nonlinear absorption (NLA) includes two effects: saturable absorption (SA) and reverse saturable absorption (RSA), which compete with each other. In previous reports, it has been observed a nonlinear optical phenomenon of switching from SA to RSA in different materials  $[17,18]$  $[17,18]$  $[17,18]$ . We believe that it is necessary to investigate the nonlinear optical properties of  $CuAlO<sub>2</sub>$ , which is of great significance for its applications in optical switching, optical limiting and other fields.

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In this work, we prepared Cu–Al–O thin films by magnetron sputtering, followed by thermal treatment. The nonlinear optical properties of the films before and after thermal treatment were investigated by the open aperture (OA) Z-scan method, and the nonlinear absorption coefficients (*β*) were further estimated.

#### **2. Experimental**

Cu–Al–O thin films were prepared on soda-lime glass by magnetron sputtering at room temperature. The sputtering target was copper–aluminum (50/50 at%) alloy with a purity of 99.99% and the sputtering gas was high purity argon (99.99%). Before sputtering, the substrates were cleaned in acetone, ethanol and deionized water for 15 min, then dried in air sequentially. The target was bombarded with argon ion for 10 min to remove the oxides on the surface. The base pressure and working pressure were  $5 \times 10^{-4}$  Pa and  $6 \times 10^{-1}$  Pa, respectively [\[19](#page-6-0)]. In this experiment, the deposition time of all samples was set to 45 s and the sputtering power was 50 W, 75 W, 100 W, 125 W and 150 W, respectively. Meanwhile, the deposited samples were marked as sample 1 (S1), sample 2 (S2), sample 3 (S3), sample 4 (S4), and sample 5 (S5) in turn. Subsequently, the as-deposited films were placed in a thermal oxidation furnace at 400 ◦C for 2 h. The as-annealed films were labeled as sample 1' (S1'), sample 2' (S2'), sample 3' (S3'), sample 4' (S4′ ), sample 5' (S5').

The morphology and crystal structure of the thin films were characterized by atomic force microscopy (AFM: XE-100, Park System) and X-ray diffraction (XRD: Bruker AXS/D8 Advance system). The optical properties of the samples were studied by the UV–vis–NIR double-beam spectrophotometer (Lambda 1050, PerkinElmer, USA) with a wavelength range of 200 nm–2000 nm. Further determination of chemical composition and valence state of samples used the Thermo Scientific K-Alpha þ X-ray photoelectron spectroscopy (XPS). Properties of the third order NLO were investigated by the open aperture (OA) Z-scan system (T-Light, Menlo Systems), which have a mode-locked picosecond laser with a wavelength of 1550 nm, a duration of 2 ps and a repetition rate of 100 MHz as the optical excitation source which is focused through a 15 mm lens, and the detector receives the signal. All the measurements were carried out at room temperature.

#### **3. Results and discussion**

#### *3.1. Structure and surface topography*

Fig. 1 shows the XRD patterns of the as-deposited and as-annealed samples. Obviously, a broad peak around 22◦ in the figure is related to the glass substrate. No other diffraction peaks are observed in the asdeposited samples (Fig. 1(a)), indicating that the deposited films were amorphous. In the vacuum environment, films were naturally oxidized due to the heat generated by the sputtering process. In addition, Reddy et al. [\[20\]](#page-6-0) reported that Cu–Al–O films formed at room temperature

were intrinsically amorphous because there was not enough thermal energy for adatoms to diffuse and nucleate on the substrate surface. Similar results were also reported by Chen et al. [\[13\]](#page-5-0). According to Fig. 1 (b), the samples were still amorphous after 400 ◦C heat treatment, because the annealing temperature was not enough to promote the crystallization of CuAlO<sub>2</sub> phase. As reported by Panthawan et al.  $[21]$  $[21]$ , no significant peak was observed at the annealing temperature lower than 400 ◦C. The Cu–Al–O phase was amorphous after annealing at 500  $°C$ , and the CuAlO<sub>2</sub> phase appeared only when the annealing tem-perature increased to 600 ℃ [[22,23](#page-6-0)].

The surface morphology of Cu–Al–O thin films before and after thermal oxidation was analyzed by AFM, as shown in [Fig. 2\(](#page-2-0)a-f). It can be obtained from [Fig. 2\(](#page-2-0)a-c) that the root mean square (RMS) surface roughness of as-deposited samples (S1–S3) are 371.965 p.m., 322.855 p. m., and 230.52 p.m., respectively. The results show that the as-deposited Cu–Al–O films have good uniformity, and the density and smoothness of the films increase with the increase of sputtering power. Thermal treatment improved the surface energy of the film, enhanced the diffusion and migration of surface atoms, and improved the surface defects. Therefore, the as-annealed film became smoother and the RMS surface roughness decreases. From the line graph in Fig.  $2(g)$ , we can clearly observe the effect of thermal treatment on the surface roughness of samples. The surface roughness of the as-deposited films is negatively correlated with the increase of the deposition power, and the surface roughness of the films decreases in different degrees after thermal treatment. For example, the root mean square surface roughness of the S2 is 322.855 p.m., which decreases to 295.354 p.m. after thermal oxidization.

#### *3.2. Composition and optical properties*

[Fig. 3](#page-3-0) presents the XPS spectra of Cu–Al–O films before and after thermal treatment (S1-S3 and S1'-S3'). According to [Fig. 3](#page-3-0)(a), the XPS spectra of all samples in the scanning range of 0–1200 eV confirm the successful preparation of Cu–Al–O films. All XPS high-resolution spectra were charge-corrected with the C 1s peak at 284.8 eV as reference. [Fig. 3](#page-3-0)  (b-c) reveals the Cu 2p core energy spectra of the Cu–Al–O film. Each sample has two strong peaks at 931.83 eV and 951.71 eV, which correspond to Cu 2p  $3/2$  and Cu 2p  $1/2$  of the CuAlO<sub>2</sub> phase, respectively [[14,](#page-5-0)[24\]](#page-6-0). In addition, the two weak peaks at 933.77 eV and 954.04 eV are attributed to Cu 2p 3/2 and Cu 2p 1/2 of CuO [[25\]](#page-6-0). Although  $Cu^{2+}$  ions are detected, no obvious (quite weak) satellite peak signal is observed due to its low content. To sum up, we successfully prepared CuAlO2 thin films at room temperature, but it was difficult to obtain pure CuAlO<sub>2</sub> due to the complicated preparation environment  $[26]$  $[26]$ . In the high-resolution Al 2p XPS spectrum [\(Fig. 3\(](#page-3-0)d-e)), three peaks obtained by deconvolution belong to  $Al^0$  (at 72.1 eV),  $Al_2O_3$  (at 74.23 eV) and  $\text{Al}_2\text{O}_\text{x}/\text{Al}$  (at 76.54 eV) in sequence. After thermal treatment, Al atoms in S1–S3 were fully oxidized, and the ratio of defective  $\text{Al}_2\text{O}_\text{x}/\text{Al}$ was significantly reduced. As shown in [Fig. 3\(](#page-3-0)f), the peak of lower



**Fig. 1.** XRD patterns of **(a)** as-deposited Cu–Al–O films and **(b)** as-annealed films.

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**Fig. 2.** Atomic force microscopy images of sample S1–S3 **(a**–**c)** and S1′ -S3' **(d**–**f)**; **(g)** Variation of RMS surface roughness of samples before and after thermal oxidation.

binding energy (at 530.7  $\pm$  0.3 eV) in the O 1s spectra corresponds to oxygen vacancies (interstitial oxygen), and the peak of higher binding energy (at  $531.6 \pm 0.3$  eV) corresponds to the Al–O bond in CuAlO<sub>2</sub> [\[11](#page-5-0), [27,28\]](#page-6-0). Fitting analysis showed that the percentage of interstitial oxygen in samples S1–S3 was 44.4%, 30.28% and 38.3%, respectively. After thermal oxidation, the oxygen vacancy content increased to different degrees, and its proportions were 54.61%, 62.2% and 61.64% respectively, which was caused by the introduction of defects caused by heat treatment and the change of the surface structure of the films [\[29](#page-6-0)]. These defects and oxygen vacancies could be used to explain the variation of the third order nonlinear characteristics of the samples [[30\]](#page-6-0).

To further investigate the optical properties of the samples, the UV–Vis absorption spectra in the range of 200–2000 nm was measured, as shown in [Fig. 4](#page-3-0). A sharp absorption edge is detected in the asdeposited samples (Fig.  $4(a)$ ) at a wavelength of about 330 nm, corresponding to a peak position of approximately 440 nm, which is consistent with previous reports [\[31](#page-6-0)–33]. Obviously, the characteristic absorption peak intensity of CuAlO<sub>2</sub> increases with the increase of sputtering power. After thermal treatment, the characteristic absorption peak at 440 nm is blue-shifted to around 400 nm, and the absorbance of all samples decreased significantly. This may be due to the significant reduction of Cu content in the film after annealing (see [Fig. 3\)](#page-3-0), the Cu/Al ratio decreased, which causes the shift of the optical absorption edge to the shorter wavelength region [[12\]](#page-5-0). At the same time, the band-edge blue-shift of the as-annealed films is also attributed to the widening of the band gap, as discussed later. Notably, a broad absorption band belonging to the phase of CuO appears at the wavelength of 870 nm [\[34](#page-6-0), [35\]](#page-6-0).

The fundamental absorption, which corresponds to the electron excitation from the valence band to the conduction band, has been widely used to determine the optical bandgap of semiconductor materials. The relationship between the optical absorption coefficient (*α*) and the photon energy (*hν*) can be expressed as [\[36\]](#page-6-0):

$$
\left(\alpha h\nu\right)^n = A(h\nu\cdot E_g)
$$

Where *A* is a constant,  $\alpha$  is the absorption coefficient,  $h\nu$  is the incident photon energy, and *Еg* is the optical bandgap. The exponent n depends on the type of transition,  $n = 2$  and  $n = 1/2$  for direct and indirect transition, respectively [[37\]](#page-6-0). The linear portion of the  $(a h \nu)^{1/2}$  versus  $h \nu$ curve in [Fig. 5](#page-3-0) is extrapolated to  $\alpha = 0$  to estimate the optical bandgaps of all samples. It can be seen from [Fig. 5\(](#page-3-0)a) that with the increase of sputtering power, the *Еg* of the as-deposited Cu–Al–O film decreased from 3.58 eV to 3.02 eV. The optical band gap of all films increased after thermal treatment in [Fig. 5](#page-3-0)(b) and was estimated to be 3.74–3.22 eV. Thermal oxidation induced the increase of oxygen vacancy, the increase of carrier concentration, which widened the band gap of the

<span id="page-3-0"></span>

**Fig. 3.** (a) Full-range XPS spectra; Cu 2p spectrum of samples before **(b)** and after **(c)** thermal treatment, **(d**–**e)** Al 2p spectrum, and **(f)** O 1s spectrum of all tested samples.



**Fig. 4.** Optical absorption spectra of **(a)** as-deposited Cu–Al–O films and **(b)** as-annealed samples.



**Fig. 5.** Optical band gaps of all samples before **(a)** and after **(b)** thermal treatment.

semiconductor as the absorption edge rose to a higher energy state (blue-shifted). M. Nisha et al. [\[38](#page-6-0)] reported that the increase of the band gap with the carrier concentration can be explained by the Burstein–Moss effect [\[39](#page-6-0)]. Here, we consider that the shift of band gap is also related to the corresponding change in transmittance and particle size [[40\]](#page-6-0).

## *3.3. Nonlinear optical (NLO) properties*

The third-order nonlinear absorption properties of Cu–Al–O thin films were characterized by an open aperture Z-scan system with an excitation wavelength of 1550 nm and an excitation energy of 3.1  $\times$  $10^{-3}$  GW/cm<sup>2</sup> [[41\]](#page-6-0). [Fig. 6](#page-4-0)(a) shows the open aperture Z-scan transmittance curves of Cu–Al–O films prepared with different sputtering

<span id="page-4-0"></span>

**Fig. 6.** The open aperture (OA) Z-scan transmittance curves of **(a)** as-sputtered and **(b)** thermally treated Cu–Al–O thin films at 1550 nm wavelength; **(c**–**d)** The nonlinear absorption coefficient (β) of the films.

powers. It can be seen that the open aperture Z-scan transmittance curves of as-deposited samples (S1–S5) are peak, showing strong saturable absorption (SA). When the sputtering power is low, S1 exhibits a strong peak intensity of saturated absorption, which may be due to the enhanced interaction between the light and the material with thinner layer [[42\]](#page-6-0). After that, the sputtering power is increased to 75 w, and the peak intensity of nonlinear transmission of thin films increases with the increase of sputtering power (S2–S5 in Fig.  $6(a)$ ). The nonlinear transmission curves of the as-annealed samples are plotted from the Z-scan data, as shown in Fig. 6(b). It can be seen that the saturation absorption peak of S1' decreases significantly compared with that before thermal treatment, which may be due to the great influence of thermal oxidization on the thickness of low-power sputtering samples. The normalized transmittance of S2' has a certain increase compared with that of as-deposited S2. It is worth noting that the open-aperture Z-scan transmittance curves of S3', S4', and S5' are valley, indicating that the nonlinear absorption mechanism of the Cu–Al–O film is transformed from SA to RSA (reverse saturable absorption) [\[43](#page-6-0)]. In semiconductors, the RSA effect is mainly caused by two-photon absorption (TPA), free carrier absorption (FCA), nonlinear scattering, or a combination of these processes [\[44](#page-6-0)].

The value of the nonlinear absorption coefficient (*β*) is determined based on normalized fit results. For nonlinear absorbing materials, the total absorption under strong excitation consists of two parts: linear absorption ( $\alpha_0$ ) and nonlinear absorption ( $\beta$ ), its simple relationship is:  $\alpha = \alpha_0 + \beta I$ , where  $\alpha_0$  is the linear absorption coefficient,  $\beta$  is the nonlinear absorption coefficient and *I* is the laser intensity [[45\]](#page-6-0). The normalized transmittance  $T_{\text{Norm}}$  is calculated from the following equation [\[46](#page-6-0),[47\]](#page-6-0):

$$
T_{\text{Norm}} = 1 - \frac{\beta I_0 L_{\text{eff}}}{2\sqrt{2}\left[1 + \left(\frac{z}{z_0}\right)^2\right]}
$$

Here,  $L_{\text{eff}} = (1 - \exp(-\alpha_0 L))/\alpha_0$  is the effective thickness of the sample,  $\alpha_0 = -(1/L) \ln T_L$ , *L* is an actual thickness of the sample and  $T_L$  is a linear transmittance of the sample;  $I_0$  is the laser intensity at the focus  $(z = 0)$ ; z is the straight-line distance from the sample to the focus and  $z_0$ is the diffraction length of the beam. In Fig.  $6(c-d)$ , the nonlinear absorption coefficient *β* of all samples was plotted into a broken line diagram. The  $\beta$  values for the as-deposited samples (in Fig. 6(c)) are all negative, corresponding to the SA effect. With the increase of sputtering power, the absolute value of *β* showed an increasing trend, reaching a maximum value of  $-6.29 \times 10^{-5}$  cm/W at 150 w (S5). Except for S2', the saturable absorption of other samples is suppressed to varying degrees, and gradually converts to RSA with the increase of sputtering power. At this time, the *β* of S3', S4', and S5' were calculated to be 1.203  $\times$  10<sup>-5</sup> cm/W, 2.592  $\times$  10<sup>-5</sup> cm/W, and 2.447  $\times$  10<sup>-5</sup> cm/W respectively. As illustrated in Table 1, we compared the nonlinear absorption coefficients (*β*eff) in relevant literatures with those in this work. The nonlinear absorption coefficient of Cu–Al–O thin films prepared in this paper is  $10-10^6$  times higher than that in relevant literatures [\[48](#page-6-0)-52]. The results show that the Cu–Al–O thin films not only realize nonlinear optical absorption conversion under the induction of thermal oxidation, but also have strong nonlinear absorption intensity, which can be used as excellent nonlinear optical materials.

The conversion of nonlinear saturable absorption to nonlinear reverse saturable absorption has been reported in many literatures and its conversion mechanism has been analyzed [\[53](#page-6-0)–55]. We proposed that under the combined action of oxygen defect, quantum confinement effect and multi-photon absorption, there existed the coexistence and competition between SA and RSA [[56,57\]](#page-6-0). From the perspective of oxygen vacancy, the variation trend of nonlinear saturation absorption

**Table 1** 

Comparison of the nonlinear absorption coefficient  $\beta_{\text{eff}}$  values in this work with those reported in the relevant literature.

Sample Material	Method	Wavelength (nm)	$\beta_{\text{eff}}$ (cm/ W)	References
$Cu-AI-O$ thin film	<b>PECVD</b>	750	$-1 \times$ $10^{-6}$	[9]
$Zn_0$ 96 $Cu_0$ 04 $Al_2O_4$	Combustion	532	1.4479 $\times 10^{-4}$	<b>101</b>
AgCu/Al <sub>2</sub> O <sub>3</sub> nanofilm	PLD&RTA	400	4.50 $\times$ $10^{-11}$	[11]
$Cu_3Nb_2O_8$	Solid-state reaction	800	$7.8 \times$ $10^{-8}$	[12]
$ZnO-Cu$	Colloidal chemical synthesis	532	$2.938 \times$ $10^{-11}$	[13]
$Cu = Al = O$ films	Magnetron sputtering	1550	$2.592 \times$ $10^{-5}$	Present work

<span id="page-5-0"></span>intensity of as-deposited Cu–Al–O films was basically consistent with that of oxygen vacancy. This is because the increase of oxygen vacancy leads to the increase of carrier concentration, which enhances the third-order nonlinear saturation absorption performance of the samples [[30\]](#page-6-0). After thermal oxidation, due to the introduction of oxygen defects and the change of film surface structure [\[29](#page-6-0)], the saturation absorption intensity of the sample was further improved, see sample S2', where saturation absorption was dominant. Starting from the S3', the average particle size of the samples was less than 1 nm, which caused quantum confinement effect due to the small size effect, and it changed the electronic structure of nanocrystals and bulk materials [[58\]](#page-6-0). As the size of the nanostructure decreased, the band gap of the semiconductor increased, accompanied by two-photon absorption or multi-photon absorption [\[59](#page-6-0)]. Therefore, the reverse from SA to RSA occurred, and the third order nonlinear absorption of the samples was dominated by reverse saturation absorption [[17\]](#page-6-0).

The finite difference time domain (FDTD) method is used to further investigate the effect of thermal oxidization on the electric field distribution of Cu–Al–O films, the results are shown in Fig. 7. In the simulation, a 1550 nm laser polarized along the y-axis incident vertically into the x-y plane of the samples. Fig.  $7(a)$  represents the electric field distribution of the as-deposited Cu–Al–O film. It can be seen that the surface of the as-deposited films was smooth and compact, the electric field distribution was uniform, and the local electric field strength was 0.78. Fig. 7(b-d) show the simulated electric field distribution of the asannealed samples S1', S2' and S3' with the local electric field intensity of 1.14, 1.3 and 1.9, respectively. After thermal treatment, the surface roughness of the films decreased, and the "hot spots" formed on the local surface between the nanoparticle spacing, resulting in enhanced electric fields. The results of FDTD show that the thermal treatment can effectively enhance the electric field intensity of the samples, thereby affecting the nonlinear absorption characteristics of the samples.

#### **4. Conclusion**

In summary, the Cu–Al–O thin films were fabricated by magnetron sputtering at room temperature, and the effects of thermal treatment on the structure and optical properties of the films were investigated. The existence of CuAlO2 phase and the increase of oxygen vacancy after thermal oxidation were confirmed by XPS analysis spectrum, which resulted in the blue-shift of characteristic absorption peak and the widening of band gap. According to the measurement results of nonlinear optics, the deposited Cu–Al–O films exhibited strong saturation absorption behavior. The nonlinear absorption mechanism of the as-annealed films changed from saturation absorption to reverse saturable absorption, and the nonlinear absorption coefficient (*β*) reached the maximum  $2.592 \times 10^{-5}$  cm/W. Therefore, Cu–Al–O films with excellent nonlinear absorption properties have potential applications in optical switching, optical limiter, and mode-locking.

#### **CRediT authorship contribution statement**

**Jingjing Xu:** Writing – original draft, Software. **Qingyou Liu:** Software. **Xiao Li:** Software. **Ruijin Hong:** Writing – review & editing, Supervision. **Chunxian Tao:** Data curation. **Qi Wang:** Data curation. **Hui Lin:** Formal analysis. **Zhaoxia Han:** Data curation. **Dawei Zhang:**  Project administration, Validation.

## **Declaration of competing interest**

The authors declare that they have no known competing financial interests or personal relationships that could have appeared to influence the work reported in this paper.



**Fig. 7.** FDTD simulated electric field amplitude patterns of **(a)** as-deposited Cu–Al–O film and as-annealed films **(b)** S1′ , **(c)** S2′ , **(d)** S3'.

#### **Data availability**

Data will be made available on request.

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